

Docket No.: 1220.1001

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Kenichi SHIRAI SHI

Group Art Unit:

US Serial No. 10/589,437

Examiner:

Filed: August 15, 2006

For: EXPOSURE APPARATUS, SUPPLY METHOD AND RECOVERY METHOD,
EXPOSURE METHOD, AND DEVICE PRODUCING METHOD

PRELIMINARY AMENDMENT

Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

Sir:

Before examination of the above-identified application, please amend the application as follows: